Press Release

Rigaku Innovative Technologies
Presents Latest Innovations at 2017
SPIE Photomask Technology Conference

September 12, 2017, Monterey, CA. — Rigaku Innovative Technologies (RIT), a leading global supplier of multilayer optics for EUV lithography (EUVL), is pleased to announce its attendance at the SPIE Photomask Technology + Extreme Ultraviolet Lithography 2017 meeting in Monterey, California.

SPIE is the international society for optics and photonics. The event takes place at the Monterey Marriott, Monday through Thursday September 11 – 14, 2017. RIT will be presenting its high-reflectivity and precision coatings for collector, illumination, imaging and analysis optics for EUV lithography at booth 117.

RIT is the components division of Rigaku Corporation, and is a global supplier of high-performance multilayer optics used in commercial and academic institutions and government research facilities. RIT manufactures the most widely used brand of multilayers and X-ray source systems in the world for hard and soft X-ray analysis of liquid, powder or solid samples.

Among the papers presented at the event will be “High-precision MoSi multilayer coatings for radial and 2D symmetric designs on curved optics” (10450-76, Session P6Tue) by Michael D. Kriese, Yang Li, and Yuri Y. Platonov of RIT. The paper details recent results in the production of a variety of high-precision multilayer coatings achieved to support the development of industrial infrastructure for EUV lithography.

About RIT
RIT is at the forefront of multilayer optic technology for EUV lithography. Formerly Osmic Inc., RIT was the first commercial supplier of multilayer optics for X-ray sciences. Since 1993, RIT has been a global leader in the development and supply of EUV optics, thus shaping the vision of EUVL for high-volume manufacturing. With hundreds of major innovations to its credit, Rigaku and its subsidiary companies are world leaders in the fields of small molecule and protein crystallography, X-ray spectrometry and diffraction, X-ray optics, as well as semiconductor metrology. Rigaku employs over 1,400 people globally and its products are in use in more than 90 countries – supporting research, development, production control and quality assurance activities. Throughout the world, Rigaku continuously promotes partnerships, dialog, and innovation within the global scientific and industrial community.

For additional information about RIT and its EUV related products, please visit:

www.rigaku.com/products/optics/euv

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